

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 7,247,248 B2
APPLICATION NO. : 10/516927
DATED : July 24, 2007
INVENTOR(S) : Tee et al.

Page 1 of 1

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 2, Line 56 – Replace “silicon I” with --silicon 1--.

Column 4, Line 27 – Replace “A method of...” with --A method of forming silicon atomic force microscope tips including the steps of:--.

Column 5, Line 22 – Replace “is and electrochemical” with --is an electrochemical--.

Signed and Sealed this

Fifteenth Day of April, 2008

A handwritten signature in black ink, appearing to read "Jon W. Dudas". The signature is stylized with a large, looped initial "J" and a cursive "Dudas".

JON W. DUDAS
Director of the United States Patent and Trademark Office